

**AUTHOR INDEX**

Ahmad, N., 397  
Bailey, G., 233  
Beaufort, D., 259  
Beck, M. S., 1  
Bergveld, P., 119, 309  
Chan, H. T., 361  
Conesa, J., 337  
de Bruijn, J. M., 259  
de Rooij, N. F., 59, 157  
Dražić, G., 407  
Duffy, C. J., 17  
Egashira, M., 349  
Ema, K., 291  
Fernández, A., 337  
Frith, B., 1  
Gardner, J. W., 361, 373  
Gernet, S., 59, 157  
Gilderman, V. K., 115  
González-Elipe, A. R., 337  
Greve, J., 119  
Hattori, S., 297  
Hetrick, R. E., 131  
Hickman, D., 17  
Hiro, K., 285  
Hök, B., 389  
Hoogeboom, P. J., 259  
Huijsing, J. H., 259  
Iwanaga, H., 349  
Janata, J., 415  
Janata, P., 415  
Josowicz, M., 415  
Kanda, Y., 247  
Kanehara, N., 349  
Karube, I., 297  
Kerkvliet, H., 195  
Ko, W. H., 207  
Kohl, D., 71  
Kooyman, R. P. H., 119  
Kopystynski, P., 239  
Kordić, S., 179  
Koudelka, M., 59, 157  
Kreit, D., 233  
Lampe, U., 269  
Lian-Zhong Yu, 221  
Lichtman, D., 397  
Manwell, J., 233  
Meijer, G. C. M., 195  
Min-Hang Bao, 149, 221  
Miyagi, H., 329  
Miyahara, Y., 329  
Moriizumi, T., 291  
Müller, J., 269  
Muñoz, A., 337  
Munuera, G., 337  
Nakamoto, T., 291  
Nooder, V., 195  
Obermeier, E., 239  
Omotosho, O. J., 1  
Palguev, S. F., 115  
Parsons, P., 233  
Plaskowski, A., 1  
Potje-Kamloth, K., 415  
Reinhoudt, D. N., 309  
Richards, P., 233  
Sanz, J., 337  
Schasfoort, R. B. M., 119  
Sebata, M., 329  
Shimizu, Y., 349  
Shurmer, H. V., 361  
Skowronska-Ptasinska, M., 309  
Soria, J., 337  
Sperring, D. A., 33  
Streekstra, G. J., 119  
Sudhölter, E. J. R., 309  
Suzuki, M., 297  
Tamiya, E., 297  
Tenerz, L., 389  
Tirén, J., 389  
Trontelj, M., 407  
Tsukada, K., 329  
Unwin, J., 45  
van den Berg, A., 309  
van den Boom, J. M., 179  
van der Wal, P. D., 309  
van Drecht, J., 195  
van Gelder, R., 195  
van Oudheusden, B. W., 259  
Wakida, S., 285  
Walsh, P. T., 45  
Wei-Jia Qi, 149  
Xian-Ping Wu, 207  
Yamamura, K., 247  
Yamane, M., 285  
Yan Wang, 149, 221  
Ylilammi, M., 167  
Yokoyama, K., 297  
Yokoyama, M., 291  
Zemtzov, V. I., 115

## SUBJECT INDEX

Acoustically-driven cantilever for gas sensing, 131

Aerospace applications optical displacement transducer for, 233

Alcohols application of discrimination techniques to, and tobaccos using tin-oxide sensors, 361

Anisotropic etching of (100) silicon, compensating corner undercutting in, 207

Boron nitride thin films for u.v.-sensor applications, 397

Calcium chromite Eu chromite doped with, for electrochemical O sensors, 115

Cantilever for gas sensing, acoustically-driven, 131

Cantilever beam batch-fabricated non-reverse valve with, manufactured by micro-machining of Si, 389

Ceramic sensor elements preparation and properties of, based on  $MgCr_2O_4$ , 407

Chromium preparation and properties of ceramic sensor elements based on  $MgCr_2O_4$ , 407

Compton-scattered gamma photons sensing system for non-destructive imaging using externally, 1

Conductometry exposure monitor for chlorinated hydrocarbons based on, using Pb phthalocyanine films, 45

d.c. and a.c. behaviour of ISFET, influence of immunological precipitate on, 119

Discrimination techniques application of, to alcohols and tobaccos using tin-oxide sensors, 361

Earphones Si microphones and, for hearing aids, 33

Electrical and chemical requirements for REFETs, may coincide, 309

Electrical conduction in solid-state gas sensors, 373

Electrochemical cell fabrication and characterization of planar, and its application as glucose sensor, 59

Electrochemical encapsulation for sensors, 415

Electron mediators micro glucose sensors using, immobilized on polypyrrole-modified electrode, 297

Encapsulation for sensors, electrochemical, 415

Europium chromite doped with Ca chromite for electrochemical O sensors, 115

Exposure monitor for chlorinated hydrocarbons based on conductometry using Pb phthalocyanine films, 45

Fabrication and characterization of planar electrochemical cell and its application as glucose sensor, 59

Gas sensing acoustically-driven cantilever for, 131

Gas-sensing characteristics of  $Li^+$ -doped and undoped  $ZnO$  whiskers, 349

Gas sensors electrical conduction in solid-state, 373

Gauge four-terminal for pressure sensors, geometric design rules for, 149

quasi-circular and square diaphragm Si pressure sensors, 247

Geometric design rules of four-terminal gauge for pressure sensors, 149

**Glucose microelectrode**  
 planar amperometric enzyme-based, 157

**Glucose sensor(s)**  
 using electron mediators immobilized on polypyrrole-modified electrode, micro, 297  
 fabrication and characterization of planar electrochemical cell and its application as, 59

**Hall plates**  
 offset reduction in; simulations and experiments, 179

**Hearing aids**  
 Si microphones and earphones for, 33

**Hydrocarbons**  
 exposure monitor for chlorinated, based on conductometry using Pb phthalocyanine films, 45

**Hydrogen gas-sensing**  
 mechanism of, at low temperatures using Rh/TiO<sub>2</sub> systems, 337

**Imaging**  
 sensing system for non-destructive, using externally Compton-scattered gamma photons, 1

**Immunological precipitate**  
 influence of, on d.c. and a.c. behaviour of ISFET, 119

**ISFET(s)**  
 influence of immunological precipitate on d.c. and a.c. behaviour of, 119  
 long-life multiple-, with polymeric gates, 329  
 novel Urushi matrix Na, 285

**Lead phthalocyanine films**  
 exposure monitor for chlorinated hydrocarbons based on conductometry using, 45

**Lithium**  
 gas-sensing characteristics of Li<sup>+</sup>-doped and undoped ZnO whiskers, 349

**Magnesium**  
 preparation and properties of ceramic sensor elements based on MgCr<sub>2</sub>O<sub>4</sub>, 407

**Microcomputer interfacing**  
 three-terminal integrated temperature transducer with, 195

**Microelectrode**  
 planar amperometric enzyme-based glucose, 157

**Micromachining**  
 of Si, batch-fabricated non-reverse valve with cantilever beam manufactured by, 389

**Microphones**  
 Si, and earphones for hearing aids, 33

**Monitoring of flow**  
 in pipes, integrated sensor for non-invasive, 259

**Neural-network pattern recognition**  
 odour-sensing system using quartz-resonator sensor array and, 291

**Odour-sensing system**  
 using quartz-resonator sensor array and neural-network pattern recognition, 291

**Offset reduction**  
 in Hall plates; simulations and experiments, 179

**Optical displacement transducer**  
 for aerospace applications, 233

**Optical sensor**  
 temporal coherence-based, 17

**Oxygen sensor(s)**  
 Eu chromite doped with Ca chromite for electrochemical, 115  
 made of reactively sputtered ZnO, thin-film, 269

**Photons**  
 Compton-scattered gamma, sensing system for non-destructive imaging using externally, 1

**Piezoresistance**  
 of Si, effect of shear stress on, 221

**Pipes**  
 monitoring of flow in, integrated sensor for non-invasive, 259

**Polymeric gates**  
 long-life multiple-ISFETs with, 329

**Polypyrrole**  
 -modified electrode, micro glucose sensors using electron mediators immobilized on, 297

**Pressure sensor(s)**  
 four-terminal-gauge quasi-circular and square diaphragm Si, 247  
 geometric design rules of four-terminal gauge for, 149  
 interchangeable Si, with on-chip compensation circuitry, 239

- Reducing gases
  - surface processes in detection of, with  $\text{SnO}_2$ -based devices, 71
- REFETs
  - how electrical and chemical requirements for, may coincide, 309
- Rhodium
  - mechanism of H gas-sensing at low temperatures using  $\text{Rh}/\text{TiO}_2$  systems, 337
- Sensing system
  - for non-destructive imaging using externally Compton-scattered gamma photons, 1
- Sensor array
  - odour-sensing system using quartz resonator, and neural-network pattern recognition, 291
- Sensor elements
  - preparation and properties of ceramic, based on  $\text{MgCr}_2\text{O}_4$ , 407
- Shear stress
  - on piezoresistance of Si, effect of, 221
- Silicon
  - anisotropic etching of (100) compensating corner undercutting in, 207
  - microphones and earphones for hearing aids, 33
  - piezoresistance of, effect of shear stress on, 221
  - pressure sensors
    - four-terminal-gauge quasi-circular and square diaphragm, 247
    - with on-chip compensation circuitry, interchangeable, 239
- Sodium
  - ISFET, novel Urushi matrix, 285
- Surface processes
  - in detection of reducing gases with  $\text{SnO}_2$ -based devices, 71
- Temperature transducer
  - three-terminal integrated, with microcomputer interfacing, 195
- Temporal coherence-based optical sensor, 17
- Thermodynamics of sensors, 167
- Tin dioxide
  - surface processes in detection of reducing gases with  $\text{SnO}_2$ -based devices, 71
- Tin-oxide sensors
  - application of discrimination techniques to alcohols and tobaccos using, 361
- Titanium
  - mechanism of H gas-sensing at low temperatures using  $\text{Rh}/\text{TiO}_2$  systems, 337
- Tobaccos
  - application of discrimination techniques to alcohols and, using tin-oxide sensors, 361
- Transducer(s)
  - optical displacement, for aerospace applications, 233
  - three-terminal integrated temperature, with microcomputer interfacing, 195
- Ultraviolet-sensor applications
  - boron nitride thin films for, 397
- Urushi matrix
  - Na ISFET, novel, 285
- Valve
  - batch-fabricated non-reverse, with cantilever beam manufactured by micromachining of Si, 389
- Zinc
  - gas-sensing characteristics of  $\text{Li}^+$ -doped and undoped  $\text{ZnO}$  whiskers, 349
  - thin-film O sensors made of reactively sputtered  $\text{ZnO}$ , 269



